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Form PTO-1449 U.S. DEPARTMENT OF COMMERCE (Rev. 7-80) PATENT AND TRADEMARK OFFICE LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)	ATTORNEY DOCKET NO.: 21011.0041U2	SERIAL NO. 09/997,113
	APPLICANT: Sheplak et al.	
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U.S. PATENT DOCUMENTS							
EXAMINER INITIALS		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
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FOREIGN PATENT DOCUMENTS							
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OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
A1	"Sound and Sources of Sound," Dowling et al., Ellis Horwood, Ltd., Chp. 7, 147-167 (1983) SEP 28 2002						
A2	"Design and Use of Microphone Directional Arrays for Aeroacoustic Measurements," Humphreys, Jr. et al., AIAA Paper 98-0471, 1-24 (1998)						
A3	"A Directional Array Approach for the Measurement Rotor Source Distributions with Controlled Spatial Resolution," Brooks, et al., <u>Journal of Sound and Vibration</u> Vol. 112(1):192-197 (1987)						
A4	"Aeroacoustic Measurements of a Wing-Flap Configuration," K.R. Meadows, et al., AIAA Paper 97-1595, 1-20, 1997						
A5	"Microelectromechanical Systems, Advance Materials and Fabrications Methods," <u>National Research Council</u> , NMAB-483, National Academy Press, 1997						
A6	"A Review of Silicon Microphones," R.P Scheper, A.G.H. van de Donk, W. Olthuis and P. Bergveld, <u>Sensors and Actuators A</u> Vol 44, 1-11 (1994)						
A7	"A Theoretical Study of Transducer Noise in Piezoresistive and Capacitive Silicon Pressure Sensors," R. R. Spencer, B.M. Fleischer, P.W. Barth, and J.B. Angell, <u>IEEE Transaction of Electron Devices</u> , Vol. ED-35:1289-1298, 1988						
A8	"Pressure and Wall Shear Stress Sensors for Turbulence Measurements," Kalvesten et al, Thesis, Royal Institute of Technology, Stockholm, Sweden (1996)						
A9	"Small Silicon Based Pressure Transducers for Measurements in Turbulent Boundary Layer, Lofdahl et al., <u>Experiments Fluids</u> , Vol. 17, 24-31 (1994)						
A10	"A Small -Size Silicon Microphone for Measurements in Turbulent Gas Flows," Kalvesten et al., <u>Sensors and Actuators</u> , Vol. 45, 103-108 (1994)						
A11	"A Silicon Subminiature Microphone Based on Piezoresistive Polysilicon Strain Gauges," Schellin et al., <u>Sensors and Actuators</u> , Vol. 32, 555-559 (1992)						
A12	"Low Pressure Acoustic Sensors for Airborne Sound With Piezoresistive Monocrystalline Silicon and Electrochemically etched Diaphragms," Schellin et al. <u>Sensors and Actuators</u> , Vol. 46 (47), 156-160 (1995)						



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<i>[Signature]</i>	A13	"A Wafer-Bonded, Silicon-Nitride Membrane Microphone with Dielectrically-Isolated, Single-Crystal Silicon PiezoResistors," Sheplak et al., Technical Digest, Solid-State Sensor and Actuator Workshop, Hilton Head, SC, 23-26 June 1998.
	A14	Kulite Semiconductor Products, Inc. MIC-093 specification sheet
	A15	"Large Deflections of Clamped Circular Plates Under Tension and Transitions to Membrane Behavior," Sheplak et al., <u>Journal of Applied Mechanics</u> , Vol. 65, No. 1, 107-115 (1998)
	A16	"Scaling Relations for Piezoresistive Microphones," Saini, et al., Proceedings of IMECE 2000: International Mechanical Engineering Congress and Exposition, Orlando, FL, November 5-10, 2000
	A17	"A Model of 1/f Noise in Polysilicon Resistors, S.L. Jang, <u>Solid-State Electron</u> , Vol. 33, 1155-1162 (1990)
	A18	"A Piezoresistive Microphone for Aeroacoustic Measurements," Arnold et al., Proceedings of 2001 ASME International Mechanical Engineering Congress and Exposition, New York, NY, November 11-16, 2001
EXAMINER: <i>Laura Alvaras</i>	DATE CONSIDERED:	10-18-05

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